

Law Offices of  
SENNIGER POWERS

One Metropolitan Square, 16th Floor  
St. Louis, Missouri 63102

Telephone (314) 231-5400  
Facsimile (314) 231-4342

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Applicant's Name: Henry F. Erk et al.

Serial No.: 10/665,982 Examiner: Eric Brice Chen

Filing Date: 09/18/2003 Art Unit: 1765 Confirmation No.: 5374

Application Title: PROCESS FOR ETCHING SILICON WAFERS

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MEMC 02-0051 (3032.1)  
PATENT

REPLY UNDER 37 C.F.R. 1.116  
EXPEDITED PROCEDURE  
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Henry F. Erk et al.  
Serial No. 10/665,982  
Filed September 18, 2003  
Confirmation No. 5374  
For PROCESS FOR ETCHING SILICON WAFERS  
Examiner Eric B. Chen

Art Unit 1765

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May 11, 2006

LETTER TO THE PATENT AND TRADEMARK OFFICE AFTER FINAL REJECTION

TO THE COMMISSIONER FOR PATENTS,

SIR:

In response to the final Office action mailed March 21,  
2006, please consider the following remarks.

Remarks begin on page 2 of this Letter.